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SEC.584

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of

Ki-sang Kim et al.

Group Art Unit: 1763

Serial No.: 09/237,229

Examiner: S. MacArthur

Filed: January 26, 1999

For: MULTI-CHAMBER SYSTEM HAVING COMPACT INSTALLATION SET-UP FOR AN ETCHING FACILITY FOR SEMICONDUCTOR DEVICE MANUFACTURING

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4/10/01  
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AMENDMENT

Honorable Assistant Commissioner for Patents  
Washington, D.C. 20231

Date: April 4, 2001

Sir:

In response to the non-final Office Action dated January 3, 2001, the period for response having been extended one (1) month to May 3, 2001, the following amendments and remarks are respectfully submitted in connection with the above-identified application.

RECEIVED  
APR - 6 2001  
TC 700 MAIL ROOM

In the Claims:

Please cancel claim 4 without prejudice or disclaimer of the subject matter contained therein.

The following replacement claims are respectfully submitted:

1. (Twice Amended) A multi-chamber system of an etching facility for manufacturing semiconductor devices comprising:

1'  
SMB  
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